SHEET 1 OF 5 ATTY. DOCKET NO. SERIAL NO. INFORMATION DISCLOSURE 005920 USA/ 09/943,383 CITATION IN AN PMG/PCTRL **APPLICATION** (PTO-1449) AU6 1 1 2004 APPLICANT SHANMUGASUNDRAM et al. FILING DATE GROUP August 31, 2001 2823 FOREIGN PATENT DOCUMENTS **EXAMINER'S** Translation INITIALS PATENT NO. DATE COUNTRY **SUBCLASS** CLASS EP 1 066 925 A2 01/10/01 EP OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) April 28, 2004. Written Opinion for PCT/US02/19117. (B)

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SHEET 2 OF 5

INFORMATION DISCLOSURE CITATION IN AN PE APPLICATION (PTO-1449)

ATTY. DOCKET NO. 005920 USA/ PMG/PCTRL SERIAL NO. 09/943,383

APPLICANT

SHANMUGASUNDRAM et al.

FILING DATE August 31, 2001 GROUP 2823

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SHEET 3 OF 5

INFORMATION DISCLOSURE CITATION IN AN **APPLICATION** (PTO-1449)

ATTY. DOCKET NO. 005920 USA/ PMG/PCTRL

SERIAL NO. 09/943,383

APPLICANT

SHANMUGASUNDRAM et al.

FILING DATE August 31, 2001 GROUP 2823

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